

BEST AVAILABLE COPY

Planned: A pressure setpoint deviation warning.				... more)	... more										
System	Wafer	Ch A	Ch B	Ch F	Xfer	LL A	LL B	Program	Misc	A	LL B	Program	Mis		
4 Steps for Epi				Process Recipe	H2 BAKE										
SAC ANEAL															
Step Name		Step 1		Step 2		Step 3		Step 4							
Chamber Selection		PURGE		HEAT UP		BAKE		COOL DOWN							
Step End Control		All		All		All		All							
Maximum Step Time		10 Seconds		45 Seconds		60 Seconds		30 Seconds							
Temp Mode		Target		Const Pwr: 20.00 kW		Lower PID: 1000.0 C		Lower PID: 1000.0 C		Const Pwr: 2.00 kW					
Temp Rate		PIIDs		None		Default		None		Default					
Power A		U In A: 50		A: 40		X: 40		X: 51		X: 44		X: 44		X: 51	
Power A Ramp		Constant Pwr		X		Constant Pwr		X		Constant Pwr		X		Constant Pwr	
Pressure Mode		Servo to Pressure		Control as Before		Control as Before		Control as Before		Servo to Pressure					
Target / Ramp Rate		1240.00 T		20.00 T/si						80.00 T				20.00 T/si	
Gas Names and Flows		:		:		:		:		:				:	
		:		:		:		:		:				:	
		:		:		:		:		:				:	
		:		:		:		:		:				:	
		:		:		:		:		:				:	
Proc/Vent Gas Dest.		Proc:Vent		Etch:Venti		Proc:Vent		Etch:Venti		Proc:Vent		Etch:Venti		Proc:Vent	
Main & Side Purges		M:30.00 S: 5.00w/H2		M:30.00 S: 5.00w/H2		M:20.00 S: 4.00w/H2		M:35.00 S:10.00w/H2		M:35.00 S:10.00w/H2					
		Charting control		Charting control		Charting control		Charting control		Charting control					
		Expand Step		Expand Step		Expand Step		Expand Step		Expand Step					
Step Status/Command		Valid Step / Copy		Valid Step / Copy		Valid Step / Copy		Valid Step / Copy		Valid Step / Copy					
Directory		Header		Delete		Add Before		Add After		Steps		> Add After			

EXHIBIT

B